

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

K. Hashimoto et al.

Group Art Unit: 2823

Application No.: 10/028,429

Examiner: K. Nguyen

Filed: December 28, 2001

Docket No.: 107317-00039



For: DRY ETCHING WITH REDUCED DAMAGE TO MOS DEVICE

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 17, 2003

Sir:

INTRODUCTORY COMMENTS

In reply to the Office Action mailed June 16, 2003, the period for response being extended two months from September 16, 2003, to November 16, 2002 by the attached two-month Petition for Extension of Time, please amend the above-identified application as follows.